

**[0007]** To achieve the object described above, a method for examining foreign matters in through holes in accordance with an embodiment of the present invention comprises simultaneously taking light passing through a plurality of through holes having a uniform size as image data, initially counting the number of light receiving regions, each being treated as a mass, corresponding to the imaged respective through holes, and conducting a process to determine presence or absence of foreign matters by mutually comparing areas of adjacent ones of the light receiving regions for only a work piece with a light receiving region count value being concurred with a specified value. In this case, the counting of light receiving regions may be conducted only for those of the extracted light receiving regions whose area values are within a specified range. Also, when the number of light receiving regions counted in the step of counting the number of light receiving regions does not concur with a specified value, the examination may be ended.

**[0009]** More concretely, light passing through a plurality of through holes having a uniform size is simultaneously taken as image data, the number of light receiving regions corresponding to the imaged respective through holes is initially counted, and a process to determine presence or absence of foreign matters is performed by mutually comparing areas of adjacent ones of the light receiving regions for only a work piece with a light receiving region count value being concurred with a specified value, and when the number of light receiving regions counted in the step of counting the number of light receiving regions does not concur with a specified value, the examination is ended.